Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1	("6518668").PN.	USPAT	OR	OFF	2005/02/26 14:48
L2	1	("6133142").PN.	USPAT	OR	OFF	2005/02/26 14:48
L3	286	cvd and plasma and chemical and vapor and deposition and Ti\$Al\$N	USPAT	OR	ON	2005/02/26 14:51
L4	136	cvd and plasma and chemical and vapor and deposition and Ti\$Al\$N and plug and metal and barrier	USPAT	OR	ON	2005/02/26 14:52
L5	46	cvd and plasma and chemical and vapor and deposition and Ti\$AI\$N and plug and metal and barrier and planarization and CMP	USPAT	OR	ON	2005/02/26 15:28
L6	2	cvd and plasma and chemical and vapor and deposition and Ti\$AI\$N and plug and metal and barrier and planarization and CMP and oxidation and ARC	USPAT	OR	ON	2005/02/26 14:53
L7	18	(plasma adj chemical adj vapor adj deposition) and (Ti\$Al\$N)	USPAT	OR	ON	2005/02/26 15:32
L8	18	7 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature)	USPAT	OR	ON	2005/02/26 15:47
L9	1	1 and (material or metal or Ti or AlN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AlCl or RF or sccm or temprature or cvd or pcvd)	USPAT	OR	ON	2005/02/26 15:48
L10	1	2 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature or cvd or pcvd)	USPAT	OR	ON	2005/02/26 15:50
L11	. 1	("6444542").PN.	USPAT	OR	OFF	2005/02/26 15:49
L12	1	("6630387").PN.	USPAT	OR	OFF	2005/02/26 15:50
L13	1	("5679448").PN.	USPAT	OR	OFF	2005/02/26 15:50
L14	1	11 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 15:55

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L15	. 1	12 and (material or metal or Ti or AlN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AlCl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 15:57
L16	1	13 and (material or metal or Ti or AlN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AlCl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 16:00
L17	1	("6821919").PN.	USPAT	OR	OFF	2005/02/26 15:59
L18	1	17 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 16:01
L19	1	("6812146").PN.	USPAT.	OR	OFF	2005/02/26 16:01
L20	1	19 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 16:03
L21	1	("6777305").PN.	USPAT	OR	OFF	2005/02/26 16:03
Ĺ22	1	21 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 16:04
L23	1	("6727588").PN.	USPAT	OR	OFF	2005/02/26 16:04
L24	1	23 and (material or metal or Ti or AIN or barrier or sequence or plasma or hole or via or plug or gas or hydrogen or nitrogen or Argon ot TiCl or AICl or RF or sccm or temprature or cvd or pcvd or ARC)	USPAT	OR	ON	2005/02/26 16:05
L25	1510	438/672	USPAT	OR .	ON	2005/02/26 16:05
L26	1222	438/675	USPAT	OR	ON	2005/02/26 16:05
L27	187	438/679	USPAT	OR	ON	2005/02/26 16:05
L28	1211	438/680	USPAT	OR	ON	2005/02/26 16:05

L29	611	438/681	USPAT	OR	ON	2005/02/26 16:05
L30	1079	438/683	USPAT	OR	ON	2005/02/26 16:06
L31	977	438/688	USPAT	OR	ON	2005/02/26 16:06